



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): Steve Biellak, et al.
Title: System and Methods for a Wafer Inspection System Using Multiple Angles and Multiple Wavelength Illumination
Application No.: 09/891,693 Filing Date: June 26, 2001
Examiner: Hoa Q. Pham Group Art Unit: 2877
Docket No.: TNCR.179US0 (M-10693 US) Conf. No.: 1752

Mail Stop RCE
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

RESPONSE TO OFFICE ACTION

Dear Sir/Madam:

This will respond to the Office Action mailed on October 19, 2004, setting a period for response expiring on January 19, 2005. Attached is a request for extension of time to extend the response period to expire on February 22, 2005; February 19, 2005 being a Saturday, and February 21, 2005 being a federal holiday.